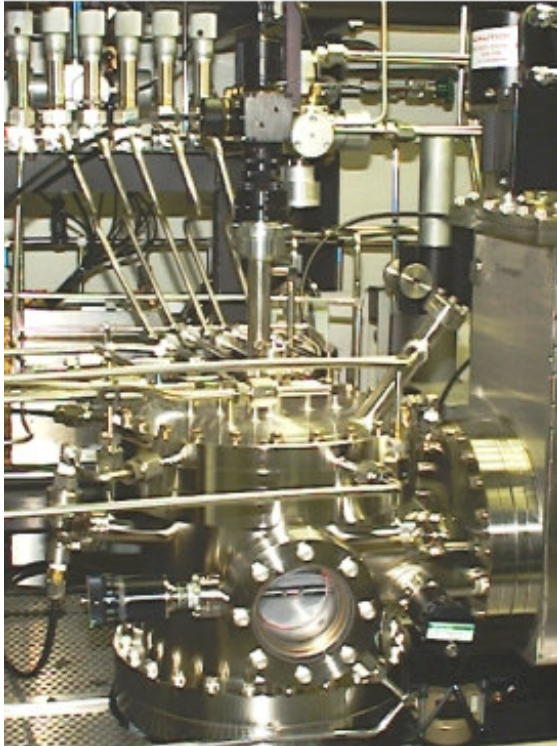


MOCVD D-125 (Originally Manufactured by EMCORE)



Recently Refurbished

**new Software, Control Hardware,
Dry Process Pump, Dry Loadlock
Pump and Heater Assembly.**

System Configuration:

Wafer capacity: Three two inch wafers.

Load lock: Loadlock chamber with hepa filter loading area.

Heater: Single zone graphite heater

Temperature control: Temperature monitor single point T/C, Eurotherm controller, single point Sekidenko Pyrometer.

Group III MO sources: TMGa - 2 units; TMIIn - 2 units; TMAI -2 units

Group V hydride sources: AsH₃ -2 lines; PH₃ -2 line.

Dopants MO: CP₂Mg -1 unit, DeZn - 1 unit

Dopants Hydride: H₂/SiH₄ - 2 lines

Neslab bath: 6 units.

Piezocon: Single channel concentration monitor for TMIIn expandable to Four channels (option).

Pump: EBARA A30;

Exhaust system: particle filter/ housing; Phosphorus trap; P-trap automatic regeneration system (option).

Gas Monitoring: CM4 4 point toxic gasmonitor.(integration option)

Software: Windows based control software.